

F-9089

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Joachim MAI, et al.

Serial No. : UNKNOWN (U.S. National Stage of
PCT/DE2004/002436)

For : METHOD AND DEVICE FOR ION BEAM
PROCESSING OF SURFACES

Group Art Unit : UNKNOWN

Examiner : UNKNOWN

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

Submitted herewith is an Information Disclosure Citation together with
copies of the documents referred to therein. The degree of relevance of the
documents referred to in the Information Disclosure Citation is set forth in the
International Search Report also submitted herewith.

10/578047

IAP12 Rec'd PCT/PTO 01 MAY 2006

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Ser. No.

No copies are provided of references which are U.S. patents or published
U.S. patent applications because they are no longer required.

Respectfully submitted,

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By



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